

MEMORY AND MANUFACTURING METHOD THEREOF

CROSS-REFERENCE TO RELATED APPLICATIONS

[001] This application claims priority to Chinese patent application No. 202010784622.3, filed on August 06, 2020 and entitled "MEMORY AND MANUFACTURING METHOD THEREOF", the disclosure of which is hereby incorporated by reference in its entirety.

TECHNICAL FIELD

[002] The embodiments of the present disclosure relate to a memory and a manufacturing method thereof.

BACKGROUND

[003] The memory is a memory part that is used for storing program and various data information. The memory may be a read only memory (ROM) and a random access memory (RAM) in terms of a usage type. A memory includes a plurality of memory cells. The memory cells may be used to store binary codes which are converted from storage information. The memory generally includes a capacitor and a transistor connected to the capacitor. The capacitor is configured to store charge representing the storage information, and the transistor is a switch that controls charge inflow and release of the capacitor. A source electrode, a drain electrode and a gate electrode are formed in the transistor, and the gate electrode is connected/coupled to a word line.

SUMMARY

[004] An embodiment of the present disclosure provides a memory, which includes:

a substrate, on which first fins and second fins are separately disposed, where at least two first fins are disposed between adjacent second fins, a spacing between the adjacent first fins is smaller than a spacing between the first fin and the second fin; a surface of the substrate is provided with an isolating structure including a first isolating structure and a second isolating structure, the first isolating structure is disposed between the adjacent first fins, and the second isolating structure is disposed between the first fin and the second fin; a dielectric layer covers tops of the first fins, side wall surfaces exposed by the isolating structure of the first fins, tops of the second fins and side wall surfaces exposed by the isolating structure of the second fins; work function layers disposed on a surface of the dielectric layer, where the work function layers on the side walls where the at least two first fins are opposite are provided with a first thickness, the work function layers on the side walls where the first fins face towards the second fins are provided with a second thickness in a direction parallel to an arrangement direction of the first fins and the second fins, and the first thickness is greater than the second thickness; and a conductive layer disposed on surfaces of the work function layers.

[005] An embodiment of the present disclosure further provides a manufacturing method of a memory, which includes: providing a substrate, on which first fins and second fins are separately disposed, where at least two first fins are disposed between adjacent second fins, a spacing between the adjacent first fins is smaller than a spacing between the first fin and the second fin; a surface of the substrate is provided with an isolating structure including a first isolating structure and a second isolating structure, the first isolating structure is disposed between the adjacent first fins, and the second isolating structure is disposed between the first fin and the second fin; forming a dielectric layer on tops of the first pins, side wall surfaces exposed by the isolating structure of the first fins, tops of the second fins and side wall surfaces exposed by the isolating structure of the second fins; forming work function layers on a surface of the dielectric layer, where the work function layers on the side walls where the at least two first fins are opposite are provided with a first thickness, the work function layers on the side walls where the first fins face towards the second fins are provided with a second thickness in a direction parallel to an arrangement direction of the first fins and the second fins, and the first thickness is greater than the second thickness; and forming a

conductive layer on surfaces of the work function layers, where a work function value of the conductive layer is smaller than work function values of the work function layers.

[006] The technical scheme provided in the embodiments of the present disclosure at least has the following advantages: the memory provided in the embodiment of the disclosure includes work function layers disposed on the surface of the dielectric layer, the work function layers on the side walls where the at least two first fins are opposite are provided with the first thickness, the work function layers on the side walls where the first fins face towards the second fins are provided with the second thickness in a direction parallel to an arrangement direction of the first fins and the second fins, and the first thickness is greater than the second thickness. Threshold voltage in an area where the adjacent first fins are opposite and an area where the first fin is opposite to the adjacent second fin may be adjusted through the thicknesses of the work function layers, the threshold voltage in the area where the two first fins are opposite is greater than the threshold voltage in the area where the first fin faces towards the (adjacent) second fin. In such a manner, fewer electrons may be transferred in a channel region between the adjacent first fins, and the stability of the memory is better.

[007] In addition, in a direction where the substrate points to the first pins, the dielectric layer and the first isolating structure are enclosed into a first filling region in the area where the adjacent first fins are opposite. The first filling region is filled up with the work function layers, that is, the side walls where the two first fins are opposite share the work function layers. In such a manner, the threshold voltage in the first filling area is greater, fewer electrons may be transferred in the channel region between the adjacent first fins, and signal interference between the two first fins is reduced.

[008] In addition, the work function layers include a first work function layer and a second work function layer, the first work function layer covers the whole surface of the dielectric layer, and the second work function layer is disposed on the first work function layer on the side walls where the at least two first fins are opposite. The thickness of the work function layer on the side walls where the two first fins are opposite is a total thickness of the first work function layer and the second work function layer. The total thickness of the first work function layer and the second work function layer is greater

than the thickness of the work function layers on the side walls where the first fins are opposite to the second fins, and therefore, the threshold voltage in the area where the adjacent first fins are opposite is greater, fewer electrons may be transferred in the channel region between the adjacent first fins, and signal interference between the adjacent first fins is smaller.

[009] The manufacturing method of the memory provided in the embodiments of the disclosure includes: work function layers are formed on the surface of the dielectric layer, the work function layers on the side walls where the at least two first fins are opposite are provided with the first thickness, and the work function layers on the side walls where the first fins face towards the second fins are provided with the second thickness in a direction parallel to an arrangement direction of the first fins and the second fins, and the first thickness is greater than the second thickness. Therefore, threshold voltage in an area where the two first fins are opposite is greater than threshold voltage in an area where the first fin faces towards the second fin, and fewer electrons may be diffused in a channel region between the two first fins. In such a manner, the signal interference between the two first fins is reduced, and the stability of the memory is better.

BRIEF DESCRIPTION OF THE DRAWINGS

[010] Exemplary description of one or more embodiments is made through pictures in the corresponding drawings thereof, which not intended to limit the embodiments. Unless specifically stated otherwise, the pictures in the drawings is not limited in proportion.

[011] FIG. 1 is a top view of a memory.

[012] FIG. 2 is a schematic sectional view of a memory along a A-A1 line in FIG. 1.

[013] FIG. 3 is a first schematic sectional view of a memory along a A-A1 line in FIG. 1 provided in a first embodiment of the present disclosure.

[014] FIG. 4 is a second schematic sectional view of a memory along a A-A1 line in

FIG. 1 provided in a first embodiment of the present disclosure.

[015] FIG. 5 is a schematic sectional view of a memory provided in a second embodiment of the present disclosure.

[016] FIG. 6 to FIG. 9 are structural schematic diagrams showing each step in a manufacturing method of a memory provided in embodiments of the present disclosure.

[017] FIG. 10 to FIG. 15 are structural schematic diagrams showing each step in another manufacturing method of a memory provided in embodiments of the present disclosure.

DETAILED DESCRIPTION

[018] It may be known from the above background art that the memory has the problem of instability.

[019] Through analysis, the major cause of the problems is that electronic signal interference between adjacent storage capacitors is more and more serious since process nodes of the memory are reduced continuously and the dimension of a shallow trench isolating structure in an active region is continuously reduced.

[020] FIG. 1 is a top view of a memory. FIG. 2 is a schematic sectional view of a memory along a A-A1 line in FIG. 1, and the A-A1 line direction is an extending direction of a word line.

[021] At present, FIG. 1 is combined with FIG. 2 for analysis. FIG. 1 shows a plurality of active regions 101, FIG. 2 shows four fins 113 and isolating structures 114 disposed between the adjacent fins 113, and the four fins in FIG. 2 correspond to sections of the four active regions 101 along the A-A1 line in FIG. 1. The depth of the isolating structure between the active regions 101 with a smaller spacing there-between is smaller due to etching and loading effect, that is, the depth of the isolating structure 114 between the two fins 113 is smaller. When a word line 100 reads, electrons e^- are generated in the channel region in the fins 113. For the two middle fins 113, since the two middle fins 113 are

close together, and the width and depth of the isolation structure 114 between the two fins 113 are relatively small, and therefore, a first diffusion path a for diffusing the electrons e^- from one fin 113 to the other fin 113 is shorter. The electrons e^- easily pass through from the below of the isolating structure 114, so that signal interference between adjacent fins 113, that is signal interference between two adjacent storage capacitors b and c, is caused, and maintenance time of the electrons in the storage capacitors is affected.

[022] According to further analysis, for the two middle fins 113, the two fins 113 include opposite first areas and second areas facing the fins 113 at the two ends, and the electrons e^- capable of being diffused in the first areas are almost as many as those capable of being diffused in the second area. If the electrons e^- capable of being diffused in channel regions of the first areas may be reduced, the mutual diffusion problem of the electrons e^- of the two fins 113 in the middle can be improved.

[023] To solve the problem, the embodiments of present disclosure provide a memory and a manufacturing method thereof. Threshold voltage in an area where the two first fins are opposite and an area where the first fin is opposite to the adjacent second fin is adjusted by adjusting thicknesses of work function layers. The thickness of the work function layers on the side walls where the adjacent first fins are opposite is greater than the thickness of the work function layers on the side walls where the first fins face towards the second fins, so that the threshold voltage in the area where the adjacent first fins are opposite is greater than the threshold voltage in the area where the first fin faces towards the (adjacent) second fin. Therefore, in a reading process of the word line 100, the threshold voltage in the area where the adjacent first fins are opposite is greater, so that fewer electrons are gathered in a channel region thereof, that is, fewer electrons may be diffused. As a result, fewer electrons are diffused between two first fins, signal interference is small, and stability of the memory is good.

[024] In order to make the purpose, technical scheme and advantages of the embodiments of the present disclosure clearer and more obvious, the embodiments of the present disclosure will be further illustrated in detail in combination with accompanying drawings hereinafter. However, those ordinary skilled in the art can understand that numerous technical details are provided in the embodiments of the present disclosure to

give the reader a fuller understanding of the present disclosure. The claimed technical schemes of the present disclosure also may be realized without the technical details and various changes and modifications based on the following embodiments.

[025] A first embodiment of the present disclosure provides a memory, FIG.3 and FIG. 4 are structural schematic diagrams of a memory provided in the first embodiment of the present disclosure. FIG. 3 is a first schematic sectional view of a memory along a A-A1 line in FIG. 1, and FIG. 4 is a second schematic sectional view of a memory along a A-A1 line in FIG. 1.

[026] Referring to FIG. 3 and FIG. 4, in the embodiments, the memory includes: a substrate 102, first fins 103 and second fins 104 separately disposed on the substrate 102, a dielectric layer 108, work function layers 109, and a conductive layer 110. At least two first fins 103 are disposed between the adjacent second fins 104, and a spacing between the adjacent first fins 103 is smaller than a spacing between the first fin 103 and the second fin 104. A surface of the substrate 102 is provided with an isolating structure 105, which includes a first isolating structure 106 and a second isolating structure 107, the first isolating structure 106 is disposed between the adjacent first fins 103, and the second isolating structure 107 is disposed between the first fins 103 and the second fins 104. The dielectric layer 108 covers tops of the first fins 103, side wall surfaces exposed by the isolating structure 105, tops of the second fins 104 and side wall surfaces exposed by the isolating structure 105. The work function layers 109 are disposed on a surface of the dielectric layer 108, the work function layers 109 on walls where the at least two first fins 103 are opposite are provided with a first thickness, and the work function layers 109 on side walls where the first fins 103 face towards the second fins 104 are provided with a second thickness in a direction parallel to an arrangement direction of the first fins 103 and the second fins 104. The first thickness is greater than the second thickness. The conductive layer 110 is disposed on surfaces of the work function layers 109.

[027] The memory provided in the embodiments will be described in detail in conjunction with the accompanying figures hereafter.

[028] In the embodiments, the arrangement direction of the first fins 103 and the second fins 104 is identical with an extending direction of a word line 100 (referring to

FIG. 1), that is, the arrangement direction is identical with the A-A1 line direction.

[029] The materials of the substrate 102 include silicon, germanium or other semiconductor materials.

[030] In the embodiments, the materials of the first fins 103 and the second fins 104 are identical with the material of the substrate 102. In other embodiments, the materials of the first fins and the second fins may be different from the materials of the substrate.

[031] The materials of the isolating structure 105 include silicon dioxide, silicon nitride, silicon carbide or other insulating materials. The first isolating structure 106 may block electron transport between the adjacent first fins 103, and the second isolating structure 107 may block the electron transport between the first fins 103 and the adjacent second fins 104.

[032] In the extending direction of the word line 100 (referring to FIG. 1), the width of the first isolating structure 106 is smaller than that of the second isolating structure 107. In a direction perpendicular to the extending direction of the word line 100 (referring to FIG. 1), the depth of the first isolating structure 106 is smaller than that of the second isolating structure 107.

[033] In the embodiments, an upper surface of the first isolating structure 106 is higher than that of the second isolating structure 107. In other embodiments, the upper surface of the first isolating structure may be flush with that of the second isolating structure.

[034] The dielectric layer 108 is taken as a gate dielectric layer of the memory. The dielectric layer 108 further covers the upper surface of the isolating structure 105. In other embodiments, the dielectric layer may not cover the upper surface of the isolating structure.

[035] The materials of the dielectric layer 108 include silicon dioxide or other high-dielectric-constant materials.

[036] Threshold voltage in an area where the adjacent first fins 103 are opposite may

be adjusted by adjusting the thickness of the work function layer 109 between the adjacent first fins 103, so that quantity of electrons capable of being diffused in a channel region between the adjacent first fins 103 is adjusted. In the embodiments, the thickness of the work function layers 109 on the side walls where the adjacent first fins 103 are opposite is greater than the thickness of the work function layers 109 on the side walls where the first fins 103 face towards the second fins 104, so that the threshold voltage in the area where the adjacent first fins 103 are opposite is greater than the threshold voltage in the areas where the first fins 103 face towards the second fins 104. In case of keeping applied working voltage unchanged, the threshold voltage is increased, electrons capable of transferring under the working voltage are reduced, and fewer electrons are gathered in the channel region, so that electron transfer between the first fins 103 can be reduced, and the mutual interference problem of memory cells is reduced.

[037] The work function layers 109 on the side walls where the at least two first fins 103 are opposite are provided with a first thickness, and the work function layers 109 on the side walls where the first fins 103 face towards the second fins 104 are provided with a second thickness in a direction parallel to an arrangement direction of the first fins 103 and the second fins 104. The first thickness is greater than the second thickness, and thickness difference may be in a range of 3 nm to 30 nm, also may be 5 nm to 20 nm or 8 nm to 15 nm. The thickness difference is kept within a larger range, so that difference between the threshold voltage in the area where the adjacent first fins 103 are opposite and the threshold voltage in the area where the first fin 103 faces towards the second fin 104 is kept within a larger range. In such a manner, electrons capable of diffusing in the channel region between the first fins 103 are fewer, and signal interference is smaller.

[038] The first thickness may be in a range of 5 nm to 50 nm, for example 10 nm, 20 nm or 40 nm. The second thickness may be in a range of 2 nm to 30 nm, for example 2 nm, 5 nm or 15 nm.

[039] Referring to FIG. 3, in a direction where the substrate 102 points to the first pins 103, the dielectric layer 108 and the first isolating structure 106 are enclosed into a first filling region in the area where the adjacent first fins 103 are opposite. In the embodiment, since the dielectric layer 108 further covers the upper surface of the first

isolating structure 106, the dielectric layer 108 is enclosed into the first filling region which is filled up with the work function layers 109. The first filling region is in a range of 8 nm to 50 nm in width, further may be 10 nm to 40 nm or 12 nm to 30 nm.

[040] Compared with a mode of only covering the side walls of the first fins 103, the first filling region are filled up with the work function layers 109. In such a manner, the threshold voltage in the area where the adjacent first fins 103 are opposite is further favorably increased, so that the electrons capable of being diffused in the channel region between the adjacent first fins 103 are reduced, and signal interference of the storage units is reduced.

[041] In other embodiments, referring to FIG. 4, a gap is formed between the work function layers 109 on the side walls where the adjacent first fins 103 are opposite.

[042] The materials of the work function layers 109 include titanium nitride, cobalt or nickel with higher work functions. Each work function layer 109 may be made of single material or a plurality of materials. In the embodiment, the materials of the work function layers 109 may be titanium nitride.

[043] The work functions of the work function layers 109 are greater than that of the conductive layer 110. The conductive layer 110 is taken as a word line, and the materials of the conductive layer include tungsten or other conductive materials.

[044] In summary, the thickness of the work function layers 109 on the side walls where the adjacent first fins 103 are opposite is greater than the thickness of the work function layers 109 on the side walls where the first fins 103 face towards the adjacent second fins 104, so that the threshold voltage in the area where the adjacent first fins 103 are opposite is greater than the threshold voltage in the area where the first fin 103 faces towards the second fin 104. In such a manner, the electrons capable of transferring and gathering in the channel region under the same working voltage are favorably reduced, so that the electrons that are transferred through the channel region are reduced. In such a manner, signal interference between the adjacent first fins 103 is reduced, and stability of the memory is improved.

[045] A second embodiment of the present disclosure provides a memory which is

substantially identical with the memory in the above-mentioned embodiment, and the main difference is that the work function layers include a first work function layer and a second work function layer. The memory provided in the second embodiment of the present disclosure will be described in detail below in combination the accompanying drawings. It should be noted that the portions corresponding to or identical with the embodiments are all the same as the previous embodiments, and herein are not described repeatedly. FIG. 5 is a schematic sectional view of a memory provided in a second embodiment of the present disclosure.

[046] Referring to FIG. 5, the memory includes: a substrate 202, first fins 203 and second fins 204 separately disposed on the substrate 202, an isolating structure 205 disposed on a surface of the substrate 202, a dielectric layer 208, work function layers 209 and a conductive layer 210. The isolating structure 205 includes a first isolating structure 206 and a second isolating structure 207, the first isolating structure 206 is disposed between the adjacent first fins 203, and the second isolating structure 207 is disposed between the first fins 203 and the second fins 204. The dielectric layer 208 covers tops of the first fins 203, side wall surfaces exposed by the isolating structure 205, tops of the second fins 204 and side wall surfaces exposed by the isolating structure 205. The work function layers 209 are disposed on a surface of the dielectric layer 208. The conductive layer 210 is disposed on surfaces of the work function layers 209.

[047] In the embodiment, the work function layers 209 include a first work function layer 211 and a second work function layer 212, the first work function layer 211 covers the whole surface of the dielectric layer 208, and the second work function layer 212 is disposed on the first work function layer 211 on the side walls where the at least two first fins 203 are opposite.

[048] The thickness of the work function layers 209 on the side walls where the adjacent first fins 203 are opposite is equal to the thickness sum of the first work function layer 211 and the second work function layer 212. The thickness sum is greater than the thickness of the work function layers 209 on the side walls where the first fins 203 are opposite to the second fins 204, so that the threshold voltage in an area where the adjacent first fins 203 are opposite is greater than the threshold voltage in an area where

the first fin 203 faces towards the second fin 204. As a result, fewer electrons are diffused in a channel region between the adjacent first fins 203, signal interference between the two first fins 203 is small, and stability of the memory is good.

[049] In the embodiment, the area where the two first fins 203 are opposite is filled up with the second work function layer 212, i.e., the second work function layer 212 is of an integrated structure, instead of two separated work function layers covering the different first fins 203, there being no gap in the second work function layer 212. In addition, filling the area where the two first fins 203 are opposite further means that the thickness of the second work function layer 212 in a direction perpendicular to the surface of the substrate 202 is greater than preset requirements, for example, height difference between a top surface of the second work function layer 212 and top surfaces of the first fins 203 is smaller than preset height difference. In other embodiments, the area where the two first fins 203 are opposite may not be filled up with the second work function layer 212.

[050] In the embodiment, the materials of the first work function layer 211 are identical with those of the second work function layer 212. Binding force between interfaces may be increased if the materials are the same, so that resistance is reduced. In other embodiments, the materials of the first work function layer may be different from those of the second work function layer.

[051] In summary, the thickness of the work function layer 209 between the two adjacent first fins 203 is the total thickness of the first work function layer 211 and the second work function layer 212. The threshold voltage in the area between the adjacent first fins 203 is increased with increase in the thickness. The electrons capable of diffusing in the channel region between the adjacent first fins 203 are fewer, so that signal interference is smaller.

[052] A third embodiment of the present disclosure provides a manufacturing method of a memory, the method is used for manufacturing the memory provided in the first embodiment. FIG. 6 to FIG. 9 are structural schematic diagrams showing each step in the manufacturing method of the memory provided in the third embodiment of the present disclosure.

- [053] Referring to FIG. 6, a substrate 302 is provided, first fins 303 and second fins 304 are separately disposed on the substrate 302, the at least two first fins 303 are disposed between the adjacent second fins 304, a spacing between the adjacent first fins 303 is smaller than a spacing between the first fin and the second fin 304, an isolating structure 305 is provided on a surface of the substrate 302, and the isolating structure 305 covers part of side walls of the first fins 303 and part of side walls of the second fins 304.
- [054] The width of a first isolating structure 306 is smaller than that of a second isolating structure 307. In addition, the greater the etched area, the greater the etched depth due to etching and loading effect, and therefore, the depth of the first isolating structure 306 is smaller than that of the second isolating structure 307.
- [055] Referring to FIG. 7, a dielectric layer 308 is formed on tops of the first fins 303 and side wall surfaces exposed by the isolating structure 305, and the dielectric layer 308 covers tops of the second fins 304 and side wall surfaces exposed by the isolating structure 305.
- [056] In the embodiment, the dielectric layer 308 further covers an upper surface of the first isolating structure 306 and an upper surface of the second isolating structure 307. In other embodiments, the dielectric layer may also not cover the upper surfaces of the first isolating structure and the second isolating structure.
- [057] Referring to FIG. 8, work function layers 309 are formed on a surface of the dielectric layer 308, in a direction parallel to an arrangement direction of the first fins 303 and the second fins 304, the work function layers 309 on the side walls where the at least two first fins 303 are opposite are provided with a first thickness, and the work function layers 309 on the side walls where the first fins 303 face towards the second fins 304 are provided with a second thickness, and the first thickness is greater than the second thickness.
- [058] In a direction where the substrate 302 points to the first pins 303, the dielectric layer 308 and the first isolating structure 306 are enclosed into a first filling region in the area where the adjacent first fins 303 are opposite. In the embodiment, since the dielectric layer 308 further covers the upper surface of the first isolating structure 306,

the dielectric layer 308 is enclosed into the first filling region. In the embodiment, the step of forming the work function layers 309 includes: the work function layers 309 are formed on the whole surface of the dielectric layer 308 until the first filling region is filled up. The deposition rate in a narrow channel region is higher than that in a wide channel region by adjusting the coverage of a deposition film, so that the work function layers 309 are formed through one process step, and the manufacturing difficulty may be reduced.

[059] It should be noted that the spacing between the two first fins 303 may be reduced in order to increase filling speed of the work function layers 309 in the first filling region.

[060] It should be noted that the work function layers may be accomplished through multiple steps. For example, the work function layers may be independently formed on the side walls where the adjacent first fins are opposite, or the work function layers may be formed on the side walls where the first fins are opposite to the second fins.

[061] Referring to FIG. 9, a conductive layer 310 is formed on surfaces of the work function layers 309, and a work function value of the conductive layer 310 is smaller than work function values of the work function layers 309.

[062] In summary, by adjusting the process step of manufacturing the work function layers 309, the thickness of the work function layers 309 on the side walls where the adjacent first fins 303 are opposite is greater than the thickness of the work function layers 309 on the side walls where the first fins 303 face towards the second fins 304, so that the threshold voltage in the area where the adjacent first fins 303 are opposite is greater than the threshold voltage in the area where the first fin 303 faces towards the second fin 304. As a result, fewer electrons are diffused in the channel region between the adjacent first fins 303, signal interference is small, and stability of the memory is good.

[063] A fourth embodiment of the present disclosure provides a manufacturing method of a memory, and the method is used for manufacturing the memory provided in the second embodiment. Different from the third embodiment, in this embodiment, a first

work function layer and a second work function layer are formed in an area where the two first fins are opposite. FIG. 10 to FIG. 15 are structural schematic diagrams showing each step in the manufacturing method of the memory provided in a third embodiment of the present disclosure. The portions corresponding to or identical with the third embodiment are all the same as the previous embodiment, and herein are not described repeatedly.

[064] Referring to FIG. 10, a first work function layer 411 is formed on a surface of a dielectric layer 408.

[065] Please refer to the third embodiment for a detailed description related to a substrate 402, first fins 403 and second fins 404 on the substrate 402, an isolating structure 405, a first isolating structure 406 and a second isolating structure 407 provided in the embodiment. Please refer to the third embodiment for a forming method of the dielectric layer 408 provided in the embodiment, which is not described repeatedly herein.

[066] Referring to FIG. 11, a sacrificial layer 413 is formed on a surface of the first work function layer 411.

[067] Referring to FIG. 12, the sacrificial layer 413 in an area where the first fins 403 are opposite is removed.

[068] Referring to FIG. 13, a second work function layer 412 is formed on the surface of the first work function layer 411 in the area where the adjacent first fins 403 are opposite. In the embodiment, the area where the two first fins 403 are opposite is filled up with the second work function area 412. That is, the second work function layer 412 is of an integrated structure, instead of two separated work function layers covering the different first fins 403, there being no gap in the second work function layer 412. In addition, filling the area where the two first fins 403 are opposite further means that the thickness of the second work function layer 412 in a direction perpendicular to a surface of the substrate 402 is greater than preset requirements, for example, height difference between a top surface of the second work function layer 412 and top surfaces of the first fins 403 is smaller than preset height difference. In other embodiments, the area where the two first fins 403 are opposite may not be filled up with the second work function

layer 412.

[069] Referring to FIG. 14, the sacrificial layer 413 in an area where the first fin 403 is opposite to the (adjacent) second fin 404 is removed (Referring to FIG. 13).

[070] Referring to FIG. 15, a conductive layer 410 is formed on surfaces of the work function layers 409.

[071] In summary, by adjusting the process step of manufacturing the work function layers 409, the first work function layer 411 and the second work function layer 412 are formed on the side walls where the adjacent first fins 403 are opposite; the total thickness of the first work function layer 411 and the second work function layer 412 is greater than the thickness of the first work function layer 411 on the side wall where the first fin 403 faces towards the second fin 404, so that the threshold voltage in the area where the adjacent first fins 403 are opposite is greater than the threshold voltage in the area where the first fin 403 faces towards the second fin 404. As a result, fewer electrons are diffused in the channel region between the adjacent first fins 403, signal interference is small, and stability of the memory is good.

[072] It should be understood by those of ordinary skill in the art that the implementation manners are specific embodiments of the present disclosure, and various changes can be made in forms and details in practical application, without departing from the spirit and scope of the present disclosure. Modifications and changes may be made by anyone skilled in the art without departing from the spirit and scope of the present disclosure, and therefore, the protection scope of the present disclosure is subject to the protection scope in claims.

CLAIMS

1. A memory, comprising:

a substrate, on which first fins and second fins are separately disposed, wherein at least two first fins are disposed between adjacent second fins, a spacing between the adjacent first fins is smaller than a spacing between the first fin and the second fin; a surface of the substrate is provided with an isolating structure comprising a first isolating structure and a second isolating structure, the first isolating structure is disposed between the adjacent first fins, and the second isolating structure is disposed between the first fin and the second fin; a dielectric layer covers tops of the first fins, side wall surfaces exposed by the isolating structure of the first fins, tops of the second fins and side wall surfaces exposed by the isolating structure of the second fins;

work function layers disposed on a surface of the dielectric layer, wherein in a direction parallel to an arrangement direction of the first fins and the second fins, the work function layers on the side walls where the at least two first fins are opposite are provided with a first thickness, the work function layers on the side walls where the first fins face towards the second fins are provided with a second thickness, and the first thickness is greater than the second thickness; and

a conductive layer disposed on surfaces of the work function layers.

2. The memory of claim 1, wherein in a direction where the substrate points to the first pins, the dielectric layer and the first isolating structure are enclosed into a first filling region in an area where the adjacent first fins are opposite, and the first filling region is filled up with the work function layers.
3. The memory of claim 1, wherein a gap is formed between the work function layers on the side walls where the at least two first fins are opposite.

4. The memory of claim 1, wherein the work function layers comprise a first work function layer covering the whole surface of the dielectric layer and a second work function layer which is disposed on the first work function layer on the side walls where the at least two first fins are opposite.
5. The memory of claim 4, wherein materials of the first work function layer are identical with materials of the second work function layer.
6. The memory of claim 1, wherein the first thickness is in a range of 5 nm to 50 nm, and the second thickness is in a range of 2 nm to 30 nm.
7. The memory of claim 1, wherein difference between the first thickness and the second thickness is in a range of 3 nm to 30 nm.
8. The memory of claim 1, wherein work functions of the work function layers are greater than a work function of the conductive layer.
9. The memory of claim 8, wherein materials of the work function layers include titanium nitride, cobalt or nickel.
10. A manufacturing method of a memory, comprising:

providing a substrate, on which first fins and second fins are separately disposed, wherein at least two first fins are disposed between adjacent second fins, a spacing between

the adjacent first fins is smaller than a spacing between the first fin and the second fin; a surface of the substrate is provided with an isolating structure comprising a first isolating structure and a second isolating structure, the first isolating structure is disposed between the adjacent first fins, and the second isolating structure is disposed between the first fin and the second fin;

forming a dielectric layer on tops of the first fins, side wall surfaces exposed by the isolating structure of the first fins, tops of the second fins and side wall surfaces exposed by the isolating structure of the second fins;

forming work function layers on a surface of the dielectric layer, wherein in a direction parallel to an arrangement direction of the first fins and the second fins, the work function layers on the side walls where the at least two first fins are opposite are provided with a first thickness, the work function layers on the side walls where the first fins face towards the second fins are provided with a second thickness, and the first thickness is greater than the second thickness; and

forming a conductive layer on surfaces of the work function layers, wherein a work function value of the conductive layer is smaller than work function values of the work function layers.

11. The manufacturing method of the memory of claim 10, wherein in a direction where the substrate points to the first pins, the dielectric layer and the first isolating structure are enclosed into a first filling region in an area where the adjacent first fins are opposite;

wherein the forming the work function layers comprise:

forming the work function layers on the whole surface of the dielectric layer until the first filling region is filled up.

12. The manufacturing method of the memory of claim 10, wherein the forming the work function layers comprises:

forming a first work function layer on the whole surface of the dielectric layer; and

forming a second work function layer which is disposed on the first work function layer on the side walls where the at least two first fins are opposite.

13. The manufacturing method of the memory of claim 12, wherein the forming the second work function layer comprises:

forming a sacrificial layer on a surface of the first work function layer;

removing the sacrificial layer in an area where the adjacent first fins are opposite;

forming the second work function layer on the surface of the first work function layer in the area where the adjacent first fins are opposite; and

removing the sacrificial layer in an area where the first fin is opposite to the second fin.